

Supporting information for

Use of CdTe Quantum Dots for High Temperature Thermal Sensing

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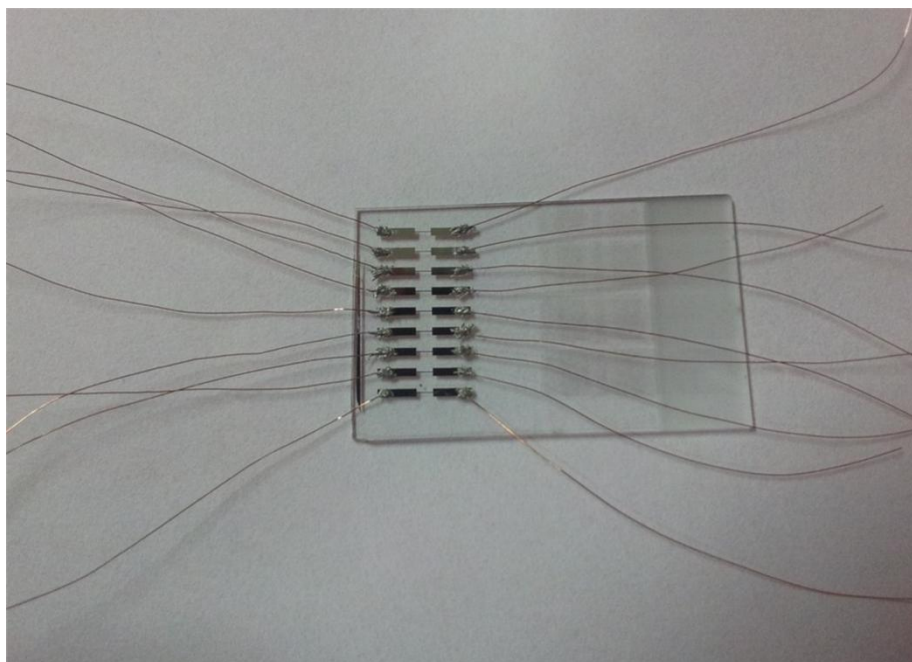


Fig. S1 Photograph of type A micro-heater electrodes connected with copper wires using electrolong. Same process was done for type B micro-heater.

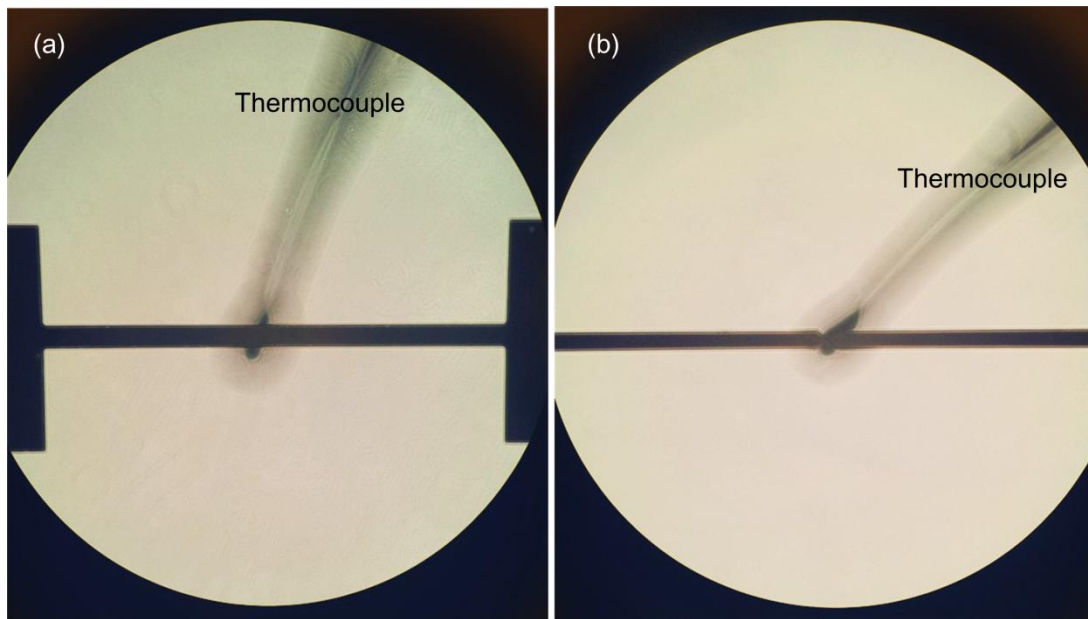


Fig. S2 Photograph of thermocouple location for type A micro-heater temperature calibration (a) and type B micro-heater thermometry validation (b) in microscopic field.